

Gp/11765

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hsiao et al.

Serial No: 09/754,235

Filing Date: January 3, 2001

Docket No: SJO990204US1

Group Art Unit: 1765

Examiner: Ahmed, Shamim

For: **CHEMICAL MECHANICAL POLISHING THICKNESS CONTROL IN MAGNETIC HEAD FABRICATION**

Box Non Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

AMENDMENT TRANSMITTAL

- ☒ Transmitted herewith is an amendment for this application.

STATUS

- ☒ Applicant is
- ☒ a small entity -- verified statement:
 - ☐ attached.
 - ☐ already filed.
 - ☒ other than a small entity.

RECEIVED
JAN 15 2003
TC 1700 MAIL ROOM

EXTENSION OF TIME

- ☐ Applicant petitions for an extension of time under 37 CFR 1.136 for the total number of months checked below:

	Extension (months)	Fee for other than small entity	Fee for small entity
<input type="checkbox"/>	one month	\$ 110.00	\$ 55.00
<input type="checkbox"/>	two months	\$ 410.00	\$205.00
<input type="checkbox"/>	three months	\$ 930.00	\$465.00
<input type="checkbox"/>	four months	\$1,450.00	\$725.00

Fee \$ _____

- ☐ If an additional extension of time is required please consider this a petition therefor.
- ☐ An extension for _____ months has already been secured and the fee paid therefor of \$ _____ is deducted from the total fee due for the total months of extension now requested.

Extension fee due with this request \$ _____

CERTIFICATE OF MAILING (37 CFR 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited on January 8, 2003 with the U.S. Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C., 20231.
Date: January 8, 2003

Patricia Beilmann
Patricia Beilmann



Applicant believes that no extension of time is required. However, this conditional petition is hereby made to provide for the possibility that applicant has inadvertently overlooked the need for a petition for extension of time.

FEE FOR CLAIMS



The fee for claims (37 CFR 1.16(b)-(d)) has been calculated as shown below:

(Col. 1)	(Col. 2)	(Col. 3)	SMALL ENTITY	OR	OTHER THAN A SMALL ENTITY	
Claims Remaining After Amendment	Highest No. Previously Paid For	Present Extra	Rate	Addit. Fee	Rate	Addit. Fee
Total *	Minus *0*	=	x9=	\$	x18=	\$
Indep. *	Minus *0*	=	x42=	\$	x84=	\$
<input type="checkbox"/> FIRST PRESENTATION OF MULTIPLE DEP. CLAIM			+140=	\$	x280=	\$
			TOTAL ADDIT. FEE	\$	OR	TOTAL ADDIT. FEE
						\$



No additional fee for claims required.



Total additional fee for claims required \$_____.

FEE PAYMENT



Attached is a check in the sum of \$_____.



Charge Account No. 08-3240 the sum of \$_____.

A duplicate of this transmittal is attached.

FEE DEFICIENCY



In the event that: a) no check to cover the filing fee is enclosed, b) any above-referenced check is inadvertently omitted or lost, or c) any enclosed check is in an amount less than or greater than the required fee, the Commissioner is authorized to charge any required fees, additional fees, or credit any overpayment to Deposit Account 08-3240. A duplicate of this authorization is enclosed for that purpose.



Attached is a postcard for date-stamped return as confirmation of receipt of these materials.

Date: January 8, 2003


ROBERT O. GUILLOT

Reg. No. 28,852

IPLO®

Intellectual Property Law Offices
1901 S. Bascom Avenue, Suite 660
Campbell, CA 95008
Telephone: (408) 558-9950
Facsimile: (408) 558-9960



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

#6/A
ma
1/16/03

Applicant: Hsiao et al.

Atty Docket: SJO990204US1

Serial No.: 09/754,235

Art Unit: 1765

Filing Date: January 3, 2001

Examiner: Ahmed, Shamim

Title: **CHEMICAL MECHANICAL POLISHING THICKNESS CONTROL IN
MAGNETIC HEAD FABRICATION**

Box Non Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

RECEIVED
JAN 15 2003
TC 1700 MAIL ROOM

FIRST AMENDMENT

Sir:

Responsive to the Office Action mailed October 8, 2002, please amend the above-identified application as follows:

In the Claims

Please delete claims 4, 16 and 28 without prejudice.

Please amend the claims by replacing the pending like numbered claims with the clean claims set forth below. A marked up version of these claims is provided in Attachment A.

-
- 1 1. (Once amended) A method for controlling the end point of the chemical mechanical
2 polishing (CMP) of a surface having a plurality of projecting components fabricated thereon,
3 comprising the steps of:
4 fabricating a plurality of upwardly projecting components upon a substrate surface;
5 fabricating a first material layer that is deposited in part upon a top surface of said
6 projecting components and in part upon a top surface of said substrate;
7 fabricating a CMP polishing end stop layer above said first material layer;
8 fabricating a polishable layer above said stop layer;